



11-15-04

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Etsuro MORITA et al.

Serial No.: 10/628,690

Filed: July 28, 2003

Art Unit: 1765

Examiner: M. J. Song

Atty. Docket No.: JG-SU-5004C/500577.20052

**METHOD OF MANUFACTURING
SILICON**

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313

RESPONSE TO RESTRICTION REQUIREMENT

Dear Sir:

In response to the Restriction Requirement Office Action mailed October 20, 2004, Applicant elects without traverse Group I, Claim 6, drawn to a method of manufacturing a silicon wafer.

Applicant reserves the right to file a divisional(s) for the claims not elected in this restriction requirement.

CERTIFICATE OF MAILING

I hereby certify that this paper (along with any document referred to as being attached or enclosed) is being:

EXPRESS MAIL

☒ deposited with the United States Postal Service on November 12, 2004, with sufficient postage as Express Mail, No. EV 398 730 937US, in an envelope addressed to Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313.

Ruth Montalvo

(Signature of person mailing paper or fee)

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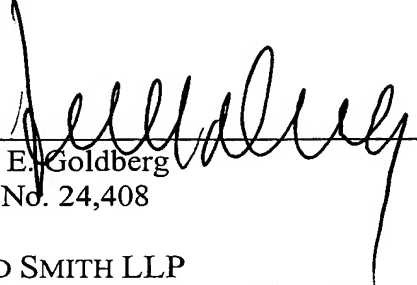
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An early and favorable action on the merits of this application is respectfully requested.

Respectfully submitted,

Dated: November 12, 2004

By


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Reg. No. 24,408

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